



Nanostrutture a confinamento quantistico elettronico: i quantum dot

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Outline

- Properties of quantum dots (QDs)
- Synthesis of quantum dots
 - Self organized epitaxial quantum dots
 - Colloidal quantum dots
- Device and applications of different types of quantum dots
- Conclusions





What is a quantum dot

- A confining potential in three dimensions whose size has no sharp definitions
- Wave nature of carriers is important (of the order De Broglie wavelength ~ 10 nm in InAs)
- Discrete states (Artificial atoms)
- Quasi zero-dimensional systems



The ideal QDs

- Precise size and shape (box or sphere) with uniform composition
- Infinite quantum confinement
- Array of identical quantum dot
- For a cubic dot (size L):







Properties of quantum dots

- Delta Function DOS
- Ground state above Bandgap
- Less active states than a bulk device of the same size
- High material gain
- Narrow and symmetrical gain
- Low optical density
- Gain saturation
- Difficult technology

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Applications of epitaxial QDs

- Improve existing devices:
 - Lasers and MCLEDs
 - Optical amplifiers
 - Long Wavelength detectors
- Novel devices and applications
 - Spintronics
 - Quantum computing
 - Quantum cryptography (single photon emitters)
 - Optical memories
- Unique physics compared to bulk semiconductors materials



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SEMICONDUCTOR QUANTUM DOTS BASED PHOTONIC DEVICES

Telecommunications and information technology demand fast and reliable data exchange on wide-world area networks	Display and Lightning technology looking for bright, high-resolution, multi-color or white emitting light sources	Pioneering studies on quantum cryptography and non-classical photon sources
↓	↓	↓
Development of optical data transmission systems requiring:	Development of:	Development of:
- low-cost	- cheap	- reliable
- 1.3 µm emitting LASER	- spectrally tunable LIGHT	- spectrally ultra-pure PHOTON
- spectrally pure SOURCES	- long-lasting SOURCES	- long-lasting SOURCES
- low-power operating	- bright	- room-temperature working
- temperature insensitive	- controlled at micron-scale	
- fast modulating		
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Synthesis of QDs

- Top-down approach
- Self-organization: Stranski Krastanov epitaxial growth
- Colloidal quantum dots





Top-down approach for QDs

•slow process, difficult to have large amount of QDs

- •Uniform QDs (limit by litography)
- •Defect states at interfaces due to etching









Bottom-up synthesis of QDs

Colloidal quantum dots

Stranski Krastanov epitaxial growth



Bottom-up synthesis of QDs



✓ <u>Stranski-Krastanow growth</u>



Growth facilities: Metal-Organic Chemical Vapor
Deposition (MOCVD) / Molecular Beam Epitaxy (MBE)

* pyramidal-shaped or lens-shaped islands; lateral size ~ 10-40 nm and heights ~5-8 nm

* room-temperature emission from single QD difficult to be achieved due to phonons energy comparable with allowed energy levels distance

✓ complete burying of QDs into solid crystalline matrix: low surface defects, high photostability, high radiative recombination rates

 \checkmark efficient electrical injection by p-n doping of the surrounding heterostructure

×_size/lfluctuation=in=@D=layers=inhomogeneous broadening



✓ Growth facilities: Schlenk line, liquid solution / Low-cost and high throughput fabrication method

✓ spherical shape with diameter ~ 2-6 nm

 higher distance among allowed energy states in conduction and valence bands: intense emission also at room temperature

 k lack of a solid matrix: spectral shifting and blinking of the single emitter / Need to insert QDs from liquid solution to solid matrices

* easy optical pumping / not straightforward electrical pumping

× inhomogeneous

Epitaxial growth techniques: MOCVD e MBE

Differences:

- Growth rate
- UHV and situ monitoring
 - safety and materials





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Self assembled QDs

Epitaxial growth: Interplay of surface energy and strain



Stranski-Krastanov 3D growth mode (strain-driven):





MOCVD QDs





EFFECT OF THE GROWTH RATE



G.R.=0.4 ML/s

G.R.=1 ML/s r ≈ 17 nm

G.R.=2 ML/s r ≈ 11 nm

6ML QDs, T=550 °C



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Effect of the Growth Temperature

-15.0 nm

7.5 nm



T=550 °C – Gr=2 ML/s



T=600 °C – Gr=2 ML/s



Synthesis of Colloidal Quantum dots





Synthesis of colloidal nanocrystals



Size dependent photoluminescence of CdSe nanocrystals







Nanocrystal size control: Colloidal nanocrystals of different materials



Epitaxial quantum dot devices for telecom applications

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Single-mode QD lasers



The saturation modal gain of the ground state results to be 36.3 $\text{cm}^{-1} \rightarrow 6 \text{ cm}^{-1}$ per QD layer

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internal losses of 4.8 cm-1 internal quantum efficiency of 23%



High modulation frequency eye patterns



Temperature dependence of eye patterns @ <u>5 Gb/s</u> Extinction ratio of 5 dB @ 15°C and 6 dB @ 85°C



Temperature dependence of eye patterns @ 10 Gb/s Extinction ratio < 5 dB @ 50°C





Single photons from single QDs



Quantum cryptography:





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Single QD devices

Shadow-mask LED:



diffusion suppressed (<100 nm) in QDs due to carrier confinement

300 nm current aperture



Fiore et als Appl. Phys. Lett. 2002

- *Down to 100 nm* current apertures with simple optical lithography
- Can tailor both current and optical confinement
- Bandgap engineering to reduce current spreading



Colloidal NCs devices and applications







Hybrid nanocomposites: magnetic and fluorescent properties combined into one single nano-object



A. Quarta, R. Di Corato, L. Manna and T. Pellegrino, Fluorescent magnetic hybrid nanostructures: preparation, properties and applications in biology, IEEE Transaction in Nanobiotechnology, *in press*





NCs dispersed in resist (ER) matrix



Highly versatile active material for optical devices

Decoupled synthesis of NCs from preparation of matrix
Complete tunability of optical properties from UV to IR range
Full control on the device geometry/Selective localization of emitters with nanometer scale resolution



Building blocks for photonic devices







Building blocks for photonic devices



Colloidal QDs: vertical microcavity by hot embossing

- Unconventional use of hot embossing techniques
- Colloidal CdSe/ZnS nanocrystals dispersed in a polymeric matrix (PMMA)
- Thermoplastic behavior of PMMA exploited in order to define the device geometry



High-temperature exposure: 10' to $180^{\circ}C \rightarrow No$ damage of the_optical properties of QDs

Insertion of SU-8 spacers between the mirrors \rightarrow Good control of the cavity length L_c

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Colloidal QDs: hybrid vertical microcavity by hot embossing



 $\mathbf{Q} = \mathbf{146}$



Localization of NCs by EBL processes

Blend deposition



Emission properties of NCs must mot be affected by electron beam

EXPOSULES atory of I.N.F.M.



L. Martiradonna et al., Microelectron. Eng., 83, 1478-1481, 2006.

SEM and AFM images of patterned blend



The positive resist behaviour of PMMA is not

perturbed by the presence of NCs





Photoluminescence maps by confocal microscope



NCs localization by lithographic techniques

Several advantages:

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- any kind of substrate without recurring to chemical or physical treatment of the surfaces;

- not only rigid substrates but also flexible devices;
- the typical resolution is defined by the lithographic process;

- the density of emitters can be easily tuned by varying the relative molar concentration of the two components (NCs – resist);

- processing by standard photolithographic techniques;

- refractive index of the blend tunable with the NCs concentration.



Colloidal QDs: Patterning of colloidal QDs by lithographic techniques

Building blocks for photonic devices



Easy implementation of multi-wavelength

devices

lithographic process on 1st NCs ensemble

> aligned lithographic process on 2nd NCs ensemble



Re-aligned lithography



Easy implementation of multi-wavelength



Easy implementation of multi-wavelength



- 1st e-beam lithography: PMMA/red NCs (λ_{peak}=640 nm, M_{NCs}=2.5·10⁻⁵ mol/l)
- 2nd photolithography: SU-8/green NCs (λ_{peak}=550 nm, M_{NCs}=7.2·10⁻⁶ mol/l)

Easy implementation of multi-wavelength devices



White emitting nanopixels

Relative intensities of R, G and B tunable with NCs concentration and





560

velicv

oreen

ourplish

bink

eddish purple

DUIDIE

viola

nteenish-14:01 (1997

560 yellaw

OF BIT OF

pink

purplish-

0.5

GUARIDA

veilowish-

600

620

770